Claims

1. (presently amended) A method of manufacturing a thin film disk comprising the steps of:

recording a first timestamp for the end of thin film deposition for the disk; waiting a predetermined time after the first timestamp to allow the thin film surface to stabilize;

applying a lubricant to the disk after the predetermined time has elapsed; recording a second timestamp for applying the lubricant to the disk; checking the second timestamp and rejecting the disk if a selected time period has been exceeded since the lubricant was applied, then performing an abrasive polishing of the disk if the selected time period has not been exceeded

performing a glide test on the disk.

since the lubricant was applied; and

- 2. (previously presented) The method of claim 1 wherein the waiting step further comprises placing the disk at a designated location and using a timing aid to alert an operator when the disk is ready for lubrication.
- 3. (previously presented) The method of claim 1 wherein the lubricant has a perfluoropolyether backbone.
- 4. (presently amended) The method of claim 1 wherein the lubricant has an end group comprising. X-CF2-O-(CF2-CF2-O) p-(CF2O) q-CF2-X-structure with X being—CH2OCH2CH(OH)CH2OH.
- 5. (presently amended) The method of claim 1 wherein the lubricant <u>comprises</u> perfluoropolyether is Fomblin Z TETRAOL.
- 6. (previously presented) The method of claim 1 wherein the disk has a thin film overcoat of diamond-like carbon.

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- 7. (presently amended) The method of claim 1 wherein the disk has a thin film overcoat comprising carbon and hydrogen of CHx.
- 8. (presently amended) The method of claim 1 wherein the disk has a thin film overcoat comprising carbon and nitrogen of CNx.
- 9. (presently amended) A method of manufacturing thin film disks comprising the steps of:

depositing at least one thin film on a disk;

reading an identifier from a carrier containing the disk;

recording a first timestamp indicative of a time when thin film deposition was completed, the first timestamp being recorded with the identifier in an automated database;

holding the carrier for a predetermined time to allow a surface of the thin film to stabilize;

after the predetermined time has elapsed, applying a lubricant to the disk; recording a second timestamp with the identifier in an automated database, the second timestamp being indicative of a time when the lubricant was applied; and

reading the identifier and rejecting the disk if more than a selected time period has elapsed after the lubricant was applied or else performing an abrasive polishing of the disk.

- 10. (previously presented) The method of claim 9 wherein the holding step further comprises placing the disk at a designated location and using a timing aid to alert an operator when the disk is ready for lubrication.
- 11. (previously presented) The method of claim 9 wherein the lubricant has a perfluoropolyether backbone.

- 12. (presently amended) The method of claim 9 wherein the lubricant has an end group comprising. X-CF2-O-(CF2-CF2-O) p-(CF2O) q-CF2-X structure with X being —CH₂OCH₂CH(OH)CH₂OH.
- 13. (presently amended) The method of claim 9 wherein the lubricant <u>comprises</u> <u>perfluoropolyether is Femblin-Z-TETRAOL</u>.
- 14. (previously presented) The method of claim 9 wherein the disk has a thin film overcoat of diamond-like carbon.
- 15. (presently amended) The method of claim 9 wherein the disk has a thin film overcoat comprising carbon and hydrogen of CHx.
- 16. (presently amended) The method of claim 9 wherein the disk has a thin film overcoat comprising carbon and nitrogen of CNx.